

**PATENT APPLICATION**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Date January 30, 2008

In re the Application of

Tsuyoshi NISHIZAWA

Group Art Unit: 1722

Application No.: 10/561,957

Examiner: S. MALEKZADEH

Filed: December 22, 2005

Docket No.: 126273

For: METHOD FOR PRODUCING SILICON EPITAXIAL WAFER AND SILICON EPITAXIAL WAFER

**LARGE ENTITY PETITION FOR 1<sup>st</sup> - 3<sup>rd</sup> EXTENSION  
OF TIME UNDER 37 C.F.R. §1.136(a) AND  
TRANSMITTAL OF FEE UNDER 37 C.F.R. §1.17**


Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is a response to the outstanding Official Action in the above-identified patent application. The shortened statutory period having expired December 27, 2007, an extension of time for a period of two months is hereby requested.

The fees associated with this filing under 37 C.F.R. §1.136(a) are being paid electronically with this filing. The Commissioner is hereby authorized to charge any additional fee (or credit any overpayment) associated with this communication to Deposit Account No. 15-0461.

Respectfully submitted,



William P. Berridge  
Registration No. 30,024

Robert M. Jackson  
Registration No. 46,796

WPB:RMJ/eks

**OLIFF & BERRIDGE, PLC**  
**P.O. Box 320850**  
**Alexandria, Virginia 22320-4850**  
**Telephone: (703) 836-6400**

<p>DEPOSIT ACCOUNT USE AUTHORIZATION Please grant any extension necessary for entry; Charge any fee due to our Deposit Account No. 15-0461</p>
--